

INFORMATION DISCLOSURE CITATION PTO-1449		ATTY. DOCKET NO.	SERIAL NO.
		P128-US	Not Yet Assigned
		APPLICANT Jonathan Doan	
SHEET 1 OF 2		FILING DATE Herewith	GROUP Not Yet Assigned

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
EC	Published Patent App No.US2002/0132 389 A1	09/19/02	Patel, et al.			
	Published Patent App No.US2003/0166 342A1	09/04/03	Chinn, et al.			
	Published Patent App No.US2003/0036 215 A1	02/20/03	Reid			
	Published Patent App No.US2003/0124 462A1	07/03/03	Miller			
	6,396,975B1	05/28/02	Wood, et al.			
	6,376,787,B1	04/23/02	Martin, et al.			
	5,709,802	01/20/98	Furuhata, et al.			
	6,024,801	02/15/00	Wallace, et al.			
	6,492,309B1	12/10/02	Behr, et al.			
✓	5,426,070	06/20/95	Shaw, et al.			

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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

EC	S. Mubassar Ali, et al., USE OF THERMAL CYCLING TO REDUCE ADHESION OF OTS COATED MEMS CANTILEVERS, 2003, pp. 151-162.
	Michael R. Houston, et al., SELF-ASSEMBLED MONOLAYER FILMS AS DURABLE ANTI-STICKTION COATINGS FOR POLYSILICON MICROSTRUCTURES, 1996, pp.42-47.
↓	In-Ha Sung, et al., MICRO/NANO-TRIBOLOGICAL CHARACTERISTICS OF SELF-ASSEMBLED MONOLAYER AND ITS APPLICATION IN NANO-STRUCTURE FABRICATION, 2003, pp.808-818
	<i>Eric Ann</i> 12/6/05

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U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
EC	6,259,551B1	07/10/01	Jacobs			
	5,936,758	08/10/99	Fisher, et al.			
	5,939,785	08/17/99	Klonis, et al.			
	6,204,085B1	03/20/01	Strumpell, et al.			
	5,512,374	04/30/96	Wallace, et al.			
↓	6,464,892B2	10/15/02	Moon, et al.			

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EC	Uthara Srinivasan, et al., LUBRICATION OF POLYSILICON MICROMECHANISMS WITH SELF-ASSEMBLED MONOLAYERS, 1998, pp.156-161.
	Uthara Srinivasan, et al., ALKYLTRICHLOROSILANE-BASED SELF-ASSEMBLED MONOLAYER FILMS FOR STICKSLIP REDUCTION IN SILICON MICROMACHINES, 1998, pp.252-260.
↓	M.P. de Boer et al., ADHESION, ADHESION HYSTERESIS AND FRICTION IN MEMS UNDER CONTROLLED HUMIDITY AMBIENTS, 1998, pp.127-129.
	C. G. Khan Malek, et al., ADHESION PROMOTION BETWEEN POLY(METHYL METHACRYLATE) AND METALLIC SURFACES FOR LIGA EVALUATED BY SHEAR STRESS MEASUREMENTS, 1998, pp.3543-3546.

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<p style="text-align: center;">INFORMATION DISCLOSURE CITATION</p> <p style="text-align: center;">APR 27 2005</p> <p style="text-align: center;">PTO-1449</p> <p style="text-align: center;">SHEET 1 OF 2</p>		ATTY. DOCKET NO.		SERIAL NO.		
		P128-US		10/766,776		
		APPLICANT Doan, et al.				
		FILING DATE 1/27/04		GROUP Not Yet Assigned		
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
 	5,939,785	8/17/99	Klonis, et al.			
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	5,447,600	9/5/95	Webb			
	5,936,758	8/10/99	Fisher, et al.			
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	2004/0100677	5/27/04	Huibers, et al.			
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
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 	W. Robert Ashurst, et al., WAFER LEVEL ANTI-STICKTION COATINGS FOR MEMS., Sensors and Actuators A 104 (2003), Pgs 213-221.					
	W. Robert Ashurst et al., VAPOR PHASE ANTI-STICKTION COATINGS FOR MEMS, Pgs 1-6.					
	W. Robert Ashurst, et al., NANOMETER-THIN TITANIA FILMS WITH SAM-LEVEL STICKTION AND SUPERIOR WEAR RESISTANCE FOR RELIABLE MEMS PERFORMANCE, 4 pgs.					
	B.C. Bunker, et al., THE IMPACT OF SOLUTION AGGLOMERATION ON THE DEPOSITION OF SELF-ASSEMBLED MONOLAYERS, 2000 American Chemical Society, Pgs 7742-7751.					
	W. Robert Ashurst, et al., ALKENE BASED MONOLAYER FILMS AS ANTI-STICKTION COATINGS FOR POLYSILICON MEMS, Berkeley Sensor & Actuator Center, 4 pgs.					
	S Imad-Uddin Ahmed, et al., USING SELF ASSEMBLED MONOLAYERS TO REDUCE FRICTION AND WEAR IN POLYSILICON BASED MEMS, 2000, Pgs. 1-18.					
	Uthara Srinivasan, et al., SELF ADDRESSED FLUOROCARBON FILMS FOR ENHANCED STICKTION REDUCTION, 1997 ieee, Pgs. 1399-1402.					
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	6,046,840	4/4/00	Huibers				
	6,844,959	1/18/05	Huibers, et al.				
	6,867,897	3/15/05	Patel, et al.				
	5,287,096	2/15/94	Thompson, et al.				
	6,204,085	3/20/01	Strumpell, et al.				
	6,300,294	10/9/01	Robbins, et al.				
✓	6,086,726	7/11/00	Renk, et al.				
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